

Supporting Information

Boosting Piezocatalytic Hydrogen Production via Bismuth Vacancy-Engineered BiOCl-Bi₂S₃ Heterojunctions Fabricated by a Light-Induced Deposition Strategy

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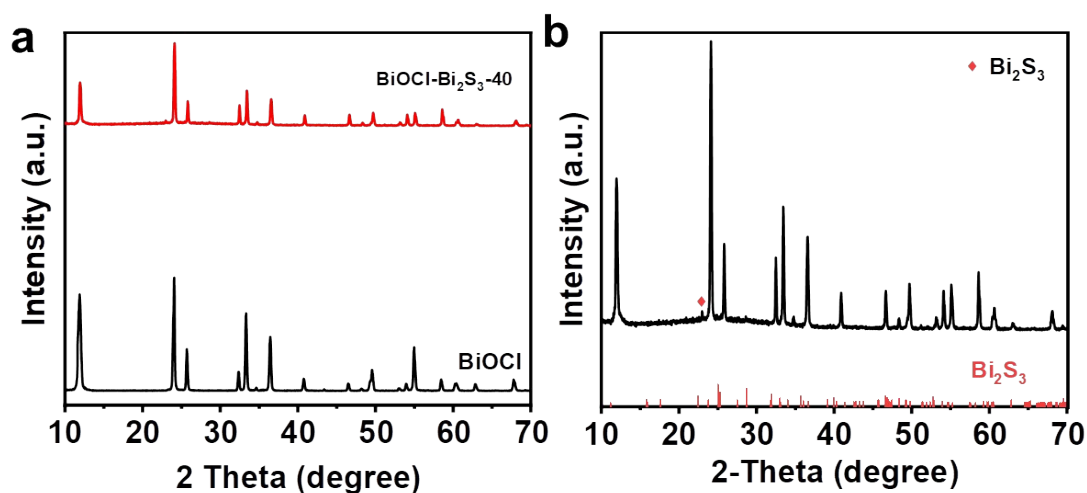


Fig. S1. (a) XRD patterns of BiOCl, and BiOCl-Bi₂S₃ heterojunction, (b) XRD patterns of BiOCl-Bi₂S₃-40.

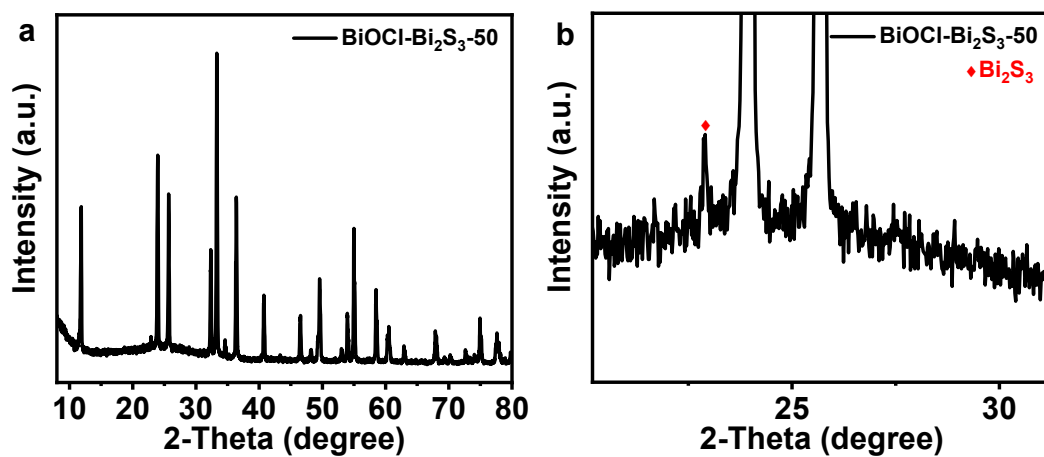


Fig. S2. (a) XRD patterns of BiOCl-Bi₂S₃-50; (b) Enlarged XRD patterns of BiOCl-Bi₂S₃-50.

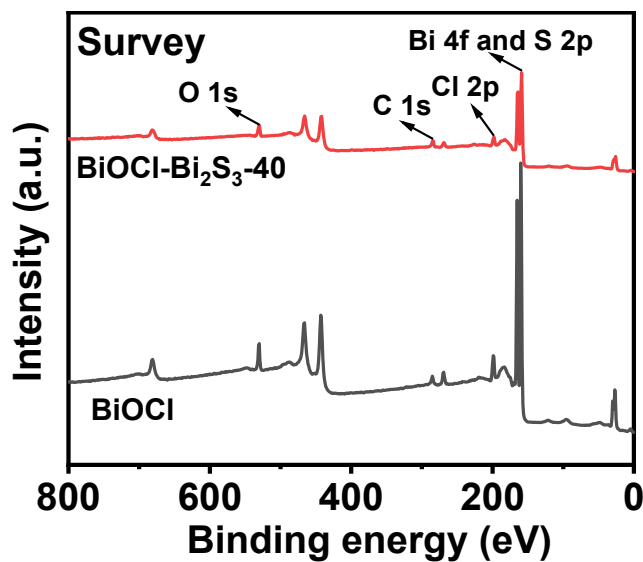


Fig. S3. XPS survey spectrum of BiOCl, and BiOCl-Bi₂S₃ heterojunctions

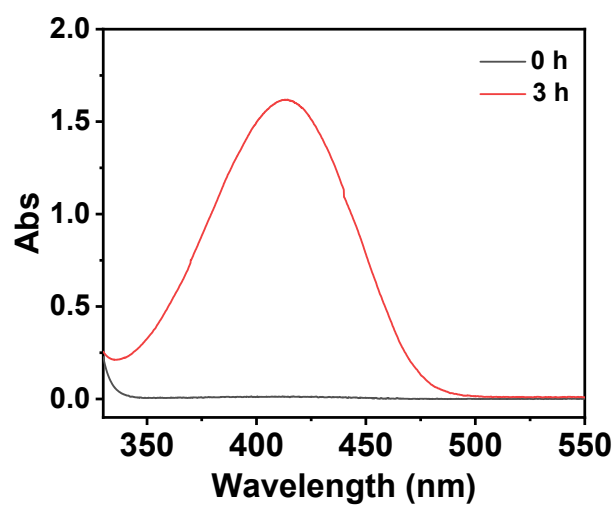


Fig. S4. UV-vis absorption spectra of methanol before and after reaction for 3 hours.

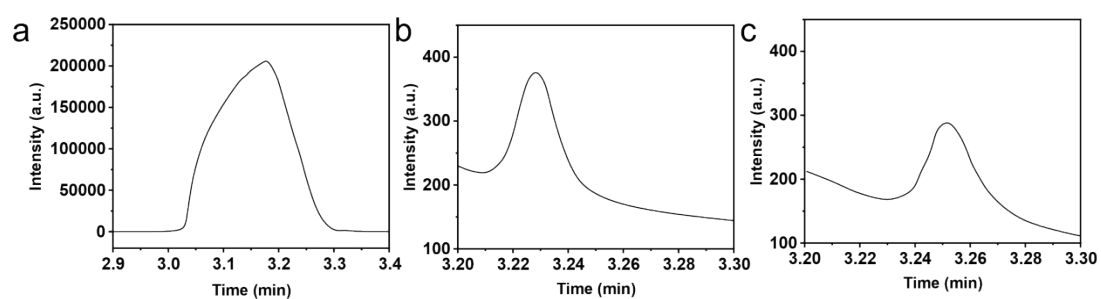


Fig. S5. (a) The GC signal for methanol oxidation product; the GC signal for oxidation product of (b) EtOH and (c) TEOA.

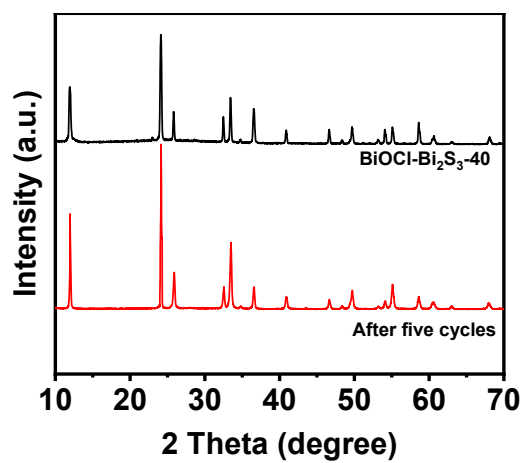


Fig. S6. XRD patterns of BiOCl-Bi₂S₃-40 before and after 5 cycles.

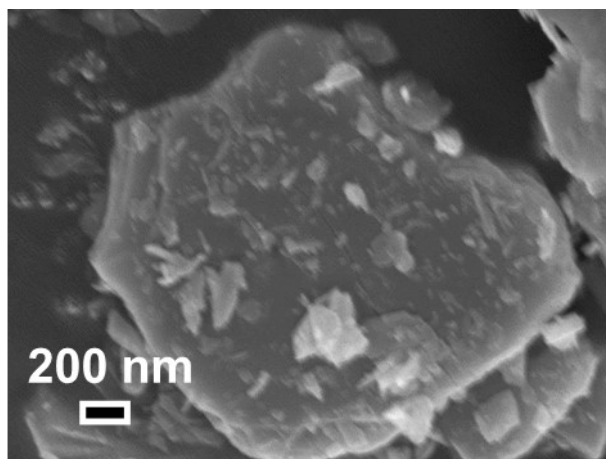


Fig. S7. SEM images of BiOCl-Bi₂S₃-40 after 5 cycles.

Table S1. Piezocatalytic H₂ production rates comparison of BiOCl-Bi₂S₃-40 heterojunction with previous reported piezocatalytic materials.

Piezocatalysts	Composition and structure	Conditions	H ₂ evolution rates (μmol/g/h)	Sacrificial Agents
BMO-0.1BTO ¹	Heterojunction	300 W	152.57	MeOH
O-MoS ₂ -180 ²	Oxygen-incorporated	40 kHz, 150 W	46.1	None
SrSn _{0.01} Ti _{0.99} O ₃ ³	Sn doped	40 kHz, 80 W	101.46	None
BSFMO-2 ⁴	Sm and Mn codoped	40 kHz, 150 W	550	TEOA
SrTiO ₃ ⁵	Oxygen Vacancy	40 kHz, 300 W	540	None
MoS ₂ ⁶	Sulfur Vacancy	40 kHz, 80 W	1423	MeOH
BIOVO/NM ⁷	Heterojunction and Oxygen Vacancy	300 W	420.6	None
Sr _{0.5} Ba _{0.5} Nb ₂ O ₆ /Sr ₂ Nb ₂ O ₇ ⁸	Heterojunction and Oxygen Vacancy	40 kHz, 110 W	109.4	TEOA
Bi _{1/2} Na _{1/2} TiO ₃ ⁹	Heterojunction and Oxygen Vacancy	40 kHz, 110 W	506.7	MeOH
BaTiO _{3-x} ¹⁰	Oxygen Vacancy	40 kHz, 110 W	132.4	None
MoS ₂ ¹¹	Vanadium-doped	68 kHz, 192 W	346.2	None
Bi ₂ S ₃ ¹²	Sulfur vacancy	40 kHz, 200 W	2370	Na ₂ S and Na ₂ SO ₃
MCC ¹³	Vacancy	50 kHz, 300 W	84.47	MeOH
BiOCl-Bi ₂ S ₃ -40 This work	Heterojunction and Bismuth Vacancy	45 kHz, 120W	678.67	None

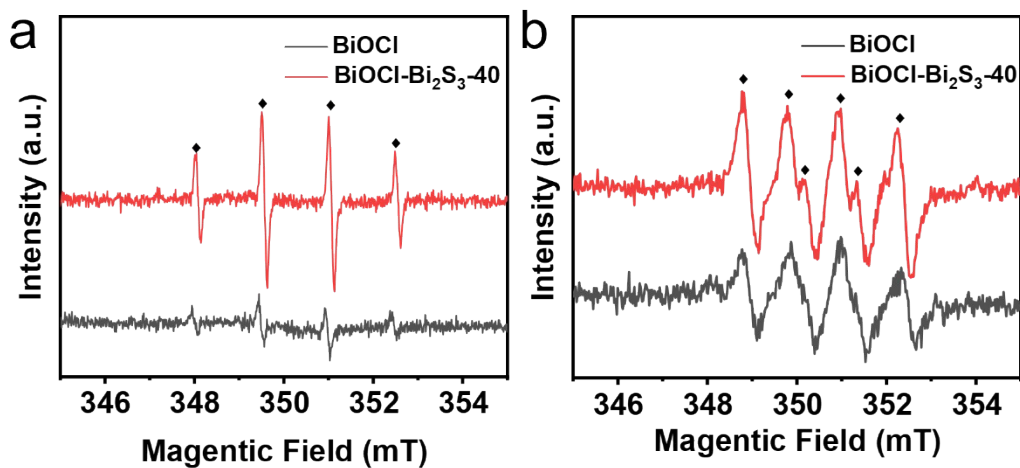


Fig. S8. EPR spectra of the samples for (a) DMPO-·OH, (b) DMPO-·O₂·.

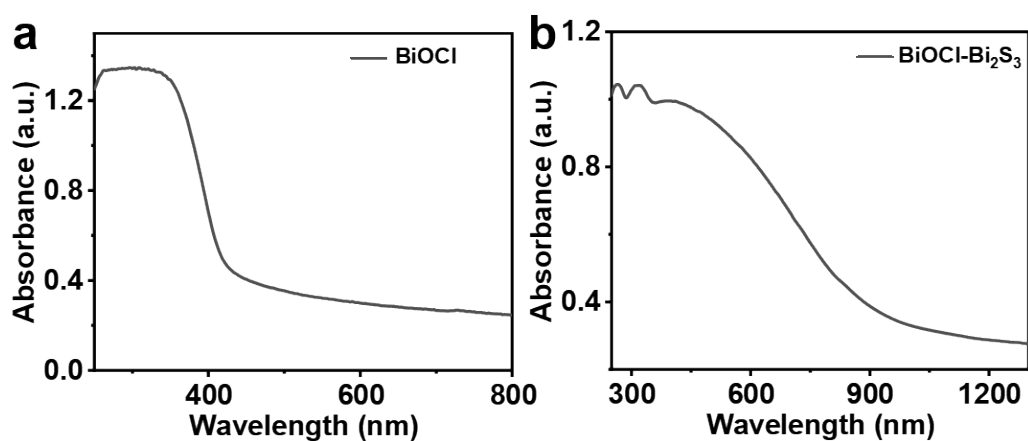


Fig. S9. UV-vis diffuse reflectance spectra (DRS) of (a) BiOCl, (b) and BiOCl-Bi₂S₃-40.

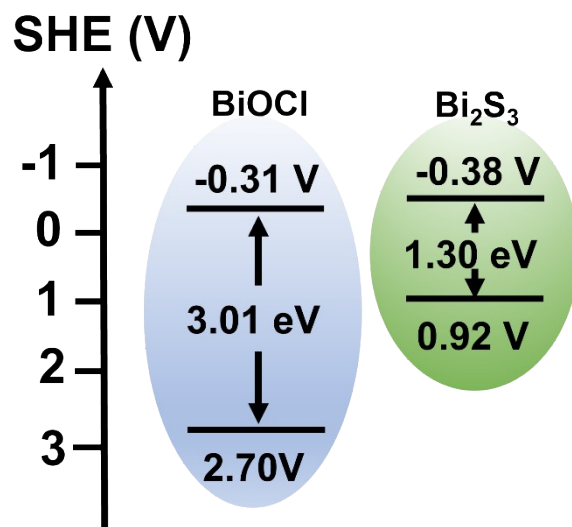


Fig. S10. Energy band diagram of BiOCl and Bi₂S₃.

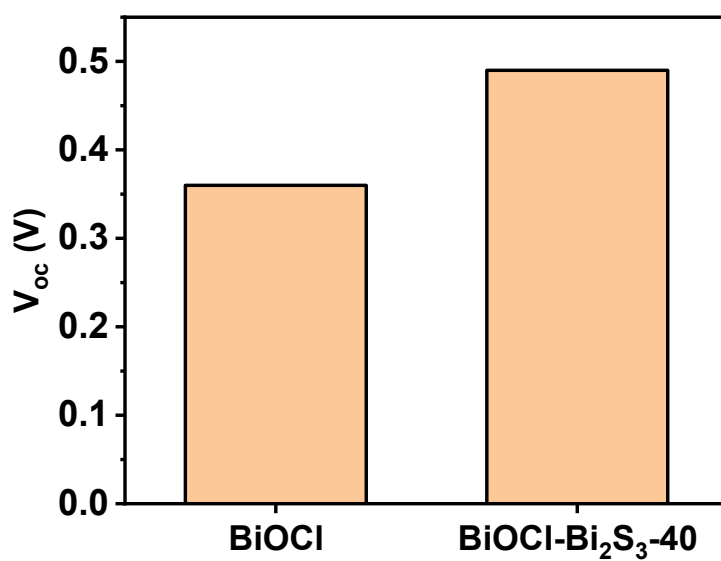


Fig. S11. The open-circuit voltage of BiOCl and BiOCl-Bi₂S₃-40.

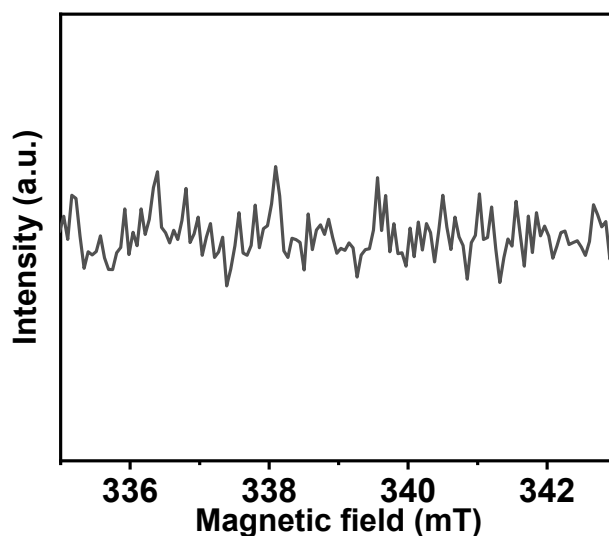


Fig. S12. EPR spectrum of 10% BiOCl- Bi₂S₃-N.

Reference.

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